## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Freese et al.

Confirmation No.: 8346

Serial No.: 10/661,917

Examiner: Daborah Chacko Davis

Filed: September 11, 2003

Group Art Unit: 1756

METHODS FOR MASTERING MICROSTRUCTURES THROUGH A

SUBSTRATE USING NEGATIVE PHOTORESIST

December 12, 2006

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## **AMENDMENT**

Sir:

The present Amendment is being filed to address the issues raised in the Official Action mailed November 14, 2006.

It is not believed that an extension of time and/or additional fee(s)-including fees for net addition of claims-are required, beyond those that may otherwise be provided for in documents accompanying this paper. In the event, however, that an extension of time is necessary to allow consideration of this paper, such an extension is hereby petitioned under 37 C.F.R. §1.136(a). Any additional fees believed to be due in connection with this paper may be charged to our Deposit Account No. 50-0220.

Amendments to the claims begin on Page 2 of this paper.

Remarks begin on Page 10 of this paper.